JAN 2 8 2002 JAN 2

In re Application of:

Yasunori INOUE et al

Serial No.: 08/921,250

Filed: August 29, 1997

RECEIVED

JAN 3 0 2002

TC 1700

7979 215102 NW

Group Art Unit: 1763

Examiner: Goudreau, G.

For: FABRICATION METHOD OF SEMICONDUCTOR DEVICE AND ABRASIVE LIQUID USED THEREIN

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents Washington, D.C. 20231

January 28, 2002

Sir:

This paper is filed to supplement the Information Disclosure Statement filed November 2, 2001. A substitute Form PTO-1449 is filed herewith which corrects the European Publication date. A copy of the cited document were previously submitted with the Information Disclosure Statement filed November 2, 2001.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. <u>01-2340</u>.

Respectfully submitted,

ARMSTRONG, WESTERMAN & HATTORI, LLP

Stephen G. Adrian Reg. No. 32,878

Atty. Docket No.: 010149

Suite 1000, 1725 K Street, N.W.

Washington, D.C. 20006

Tel: (202) 659-2930 Fax: (202) 887-0357

SGA/arf

Enclosures: PTO-1449; Reference (1)